CLAIMS

1. A management apparatus comprising:

an acquisition unit configured to acquire process information about a substrate process, the process information including process data and a process condition; and

a display control unit configured to control a display on a display apparatus, which is preferably part of the management apparatus based on the process information acquired by the acquisition unit,

wherein the display control unit is configured to selectively display, on the display apparatus, a first screen that displays the process data of a plurality of lots, each including a plurality of substrates on a lot-by-lot basis and a second screen that displays the process data of a first lot on a substrate-by-substrate basis, the first lot being a lot designated by a user from the plurality of lots displayed on the first screen,

wherein the process condition is a condition including a recipe and an apparatus parameter, the recipe being the process condition that is shared and used by a plurality of apparatuses and the apparatus parameter being the process condition that is not shared by the plurality of apparatuses, and

wherein the display control unit is configured to display, on the display apparatus, the second screen that displays the process data of the first lot and the process data of a second lot on a substrate-by-substrate basis, the second lot being processed by the same recipe as a recipe by which the first lot is processed.

2. The management apparatus according to claim 1, wherein the process data is information including a result of an operation of a processing apparatus that performs the substrate process and a state of the substrate having undergone the substrate process.

3. The management apparatus according to any one of claims 1 or 2, wherein the

display control unit is configured to display, on the display apparatus, the second screen that displays the process data of the first lot and the process data of a second lot on a substrate-by-substrate basis, the second lot being processed under the process condition including one or more process conditions that are the same as the process condition under which the first lot is processed.

4. The management apparatus according to claim 1 to 3, wherein the display control unit is configured to display, on the display apparatus, the second screen that displays the process data of the first lot and the process data of the second lot on a substrate-by-substrate basis and the process condition of the first lot and the process condition of the second lot.

5. The management apparatus according to any one of claims 1 to 4, wherein at least one of the first screen and the second screen displays the process data as a graph.

6. The management apparatus according to any one of claims 1 to 5, wherein a display method by which the second screen is displayed on the display apparatus is changeable to highlight the process condition that has a difference among the process conditions of third and fourth lots designated by the user.

7. The management apparatus according to any one of claims 1 to 6, further comprising a calculation unit configured to calculate lot-based process data based on a plurality of pieces of substrate-based process data acquired by the acquisition unit.

8. The management apparatus according to claim 7, wherein the calculation unit is configured to calculate the lot-based process data based on at least one statistical process from a maximum value, a minimum value, a mean value, a median value, and a

standard deviation of the plurality of pieces of substrate-based process data.

9. An method for processing information in a management apparatus comprising:

acquiring, in the management apparatus, process information about a substrate process, the process information including process data and a process condition; and

controlling a display on a display apparatus, which is preferably part of the management apparatus, based on the acquired process information,

wherein, control is performed to selectively display, on the display apparatus, a first screen that displays the process data of a plurality of lots, each including a plurality of substrates on a lot-by-lot basis and a second screen that displays the process data of a first lot on a substrate-by-substrate basis, the first lot being a lot designated by a user from the plurality of lots displayed on the first screen,

wherein the process condition is a condition including a recipe and an apparatus parameter, the recipe being the process condition that is shared and used by a plurality of apparatuses and the apparatus parameter being the process condition that is not shared by the plurality of apparatuses, and

wherein the display control unit is configured to display, on the display apparatus, the second screen that displays the process data of the first lot and the process data of a second lot on a substrate-by-substrate basis, the second lot being processed by the same recipe as a recipe by which the first lot is processed.

10. A program for causing a computer to execute the information processing method according to claim 9.

11. An article manufacturing system comprising:

an information processing apparatus according to any one of claims 1 to 8; and

a pattern forming apparatus configured to form a pattern on a substrate,

wherein the information processing apparatus manages a plurality of apparatuses including the pattern forming apparatus.

12. An article manufacturing method comprising:

forming a pattern on a substrate by using the article manufacturing system according to claim 11; and

performing at least one process from oxidation, film forming, vapor deposition, doping, flattening, etching, resist removing, dicing, bonding, and packaging on the substrate having the pattern formed thereon,

wherein an article is manufactured from the processed substrate.